

Electron Microscopy II

- **Transmission Electron Microscopy (TEM)**
- **Scanning Transmission Electron Microscopy (STEM)**
- **Scanning Electron Microscopy (SEM)**

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200 nm

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Electron Microscopy Methods

Transmission Electron Microscopy (TEM)

- Bright / Dark Field (BF/DF)
- High-Resolution Transition Electron Microscopy (HRTEM)
- Energy-Filtered (EFTEM)
- Electron Diffraction (ED)

Scanning Transmission Electron Microscopy (STEM)

- Bright / Dark Field (BF/DF-STEM)
- High-Angle Annular Dark Field (HAADF-STEM)

Analytical Electron Microscopy (AEM)

- X-ray Spectroscopy
- Electron Energy-Loss Spectroscopy (EELS)
- Electron Spectroscopic Imaging (ESI)

Scanning Electron Microscopy (SEM)

- Secondary Electrons (SE)
- Back-Scattered Electrons (BSE)

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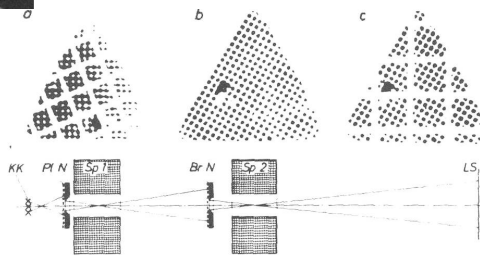
Development of the First Transmission Electron Microscope



1927 *Hans Busch*: Electron beams can be focused in an inhomogeneous magnetic field.

1931 *Max Knoll and Ernst Ruska* built the first TEM.

1986 Nobel prize for *Ruska*



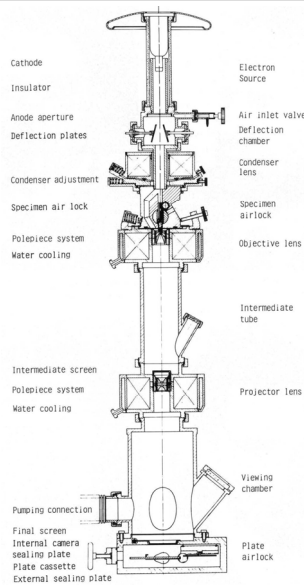
a) Einstufiges Bild eines Platin-Netzes vor Spule 1 durch Spule 1; M 130:1
 b) Einstufiges Bild eines Bronze-Netzes vor Spule 2 durch Spule 2; M 48:1
 c) Zweistufiges Bild des Platin-Netzes vor Spule 1 durch Spule 1 und Spule 2; M 174:1
 zusammen mit dem einstufigen Bild des Bronze-Netzes vor Spule 2; M 48:1

Knoll, Ruska, *Z. Phys.* **78** (1932) 318

History of Electron Microscopy

3

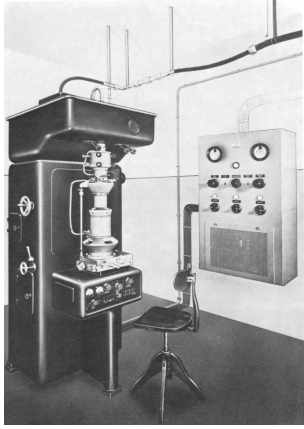
1938 First Siemens Electron Microscope (Resolution ca. 13 nm)



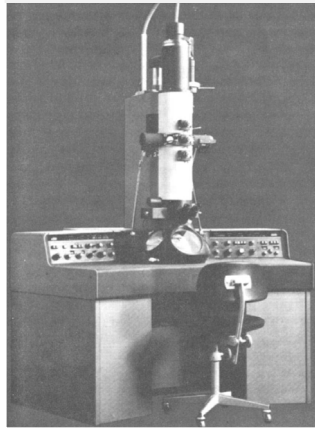
History of Electron Microscopy

4

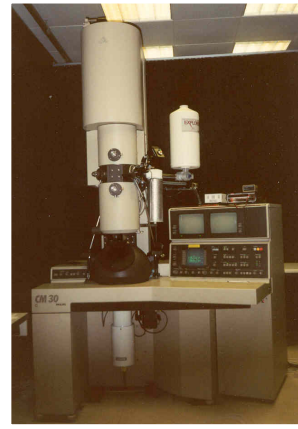
Transmission Electron Microscopes



1939: first TEM serially produced by Siemens resolution ca. 7 nm



~1970: HRTEM Philips EM400, V = 120 kV resolution ca. 0.35 nm

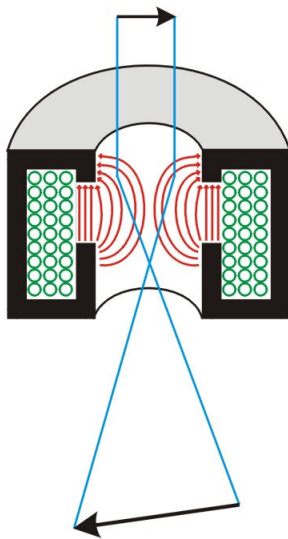


~1990 Philips CM30, V = 300 kV resolution ca. 0.2 nm

History of Electron Microscopy

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Magnetic Lens



An electron in a magnetic field (here: inhomogeneous, but axially symmetric) experiences the Lorentz force \mathbf{F} :

$$\mathbf{F} = -e (\mathbf{E} + \mathbf{v} \times \mathbf{B})$$

$$|\mathbf{F}| = e\mathbf{v}\mathbf{B}\sin(\mathbf{v},\mathbf{B})$$

\mathbf{E} : strength of electric field

\mathbf{B} : strength of magnetic field

e/\mathbf{v} : charge/velocity of electrons

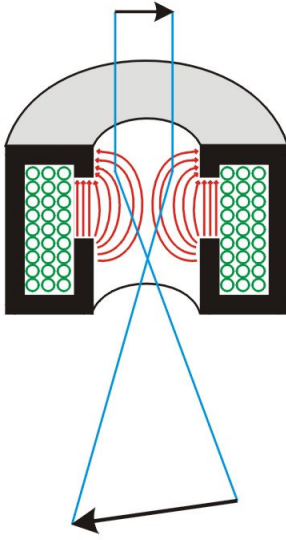
Magnetic lenses

- manipulate the electron beam
- form an image of the object

Transmission Electron Microscopy

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Magnetic Lens



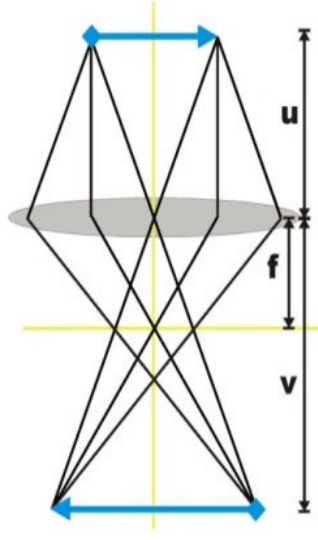
Object plane

Lens

Back focal plane

Lens problems:
spherical aberration C_s
chromatic aberration C_c
astigmatism

Light optical analogue



Object plane

Lens

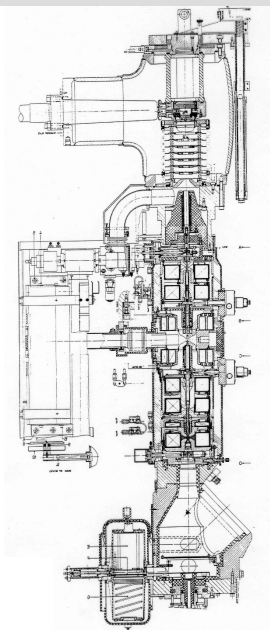
Back focal plane

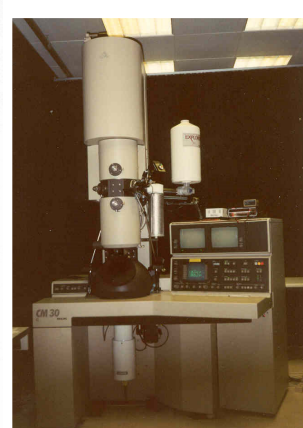
Lens equation: $1/u + 1/v = 1/f$
Magnification $M = v/u$

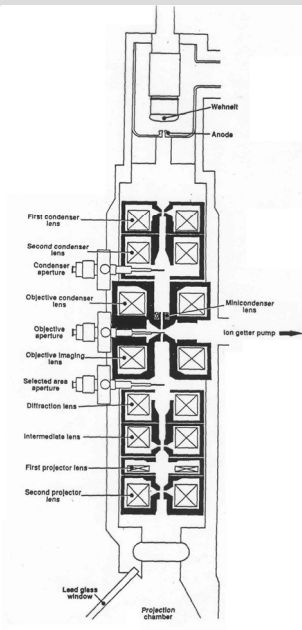
Transmission Electron Microscopy

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Cross-Section of the Column of a CM30 Microscope







- Wahneit
- Anode
- First condenser lens
- Second condenser lens
- Condenser aperture
- Objective condenser lens
- Microcondenser lens
- Objective aperture
- Objective imaging lens
- Selected area aperture
- Diffraction lens
- Intermediate lens
- First projector lens
- Second projector lens
- Lead glass window
- Projection chamber
- Ion getter pump

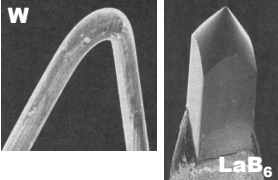
Transmission Electron Microscopy

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Electron Guns

Thermoionic Guns

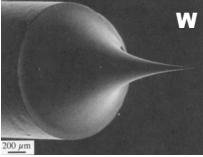
Electron emission by heating



Properties	W	LaB ₆	FEG
Work function / eV	4.5	2.4	4.5
Temperature / K	2700	2000	(300-)1800
Energy spread / eV	3-4	1.5-3	0.4-1.5
Source size / nm	30000	5000	3-20
Maximum current / nA	1000	500	(30-)300
Brightness / A/m ² sr	10 ⁹	5x10 ¹⁰	10 ¹³
Lifetime / h	100	500	>1000

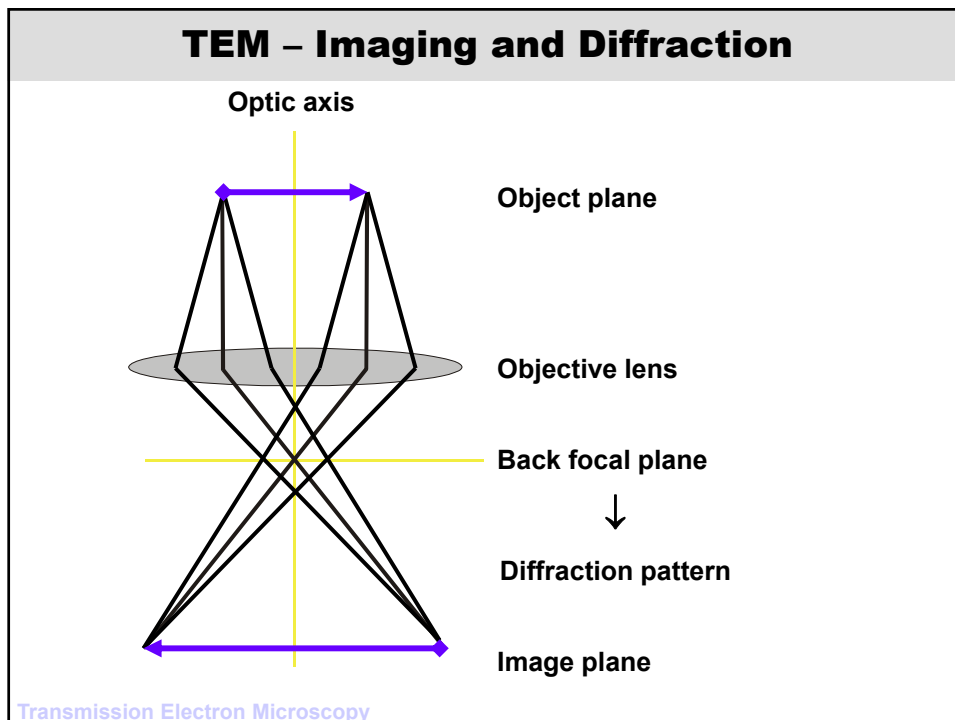
Field Emission Guns (FEG)

Electron emission by applying an extraction voltage

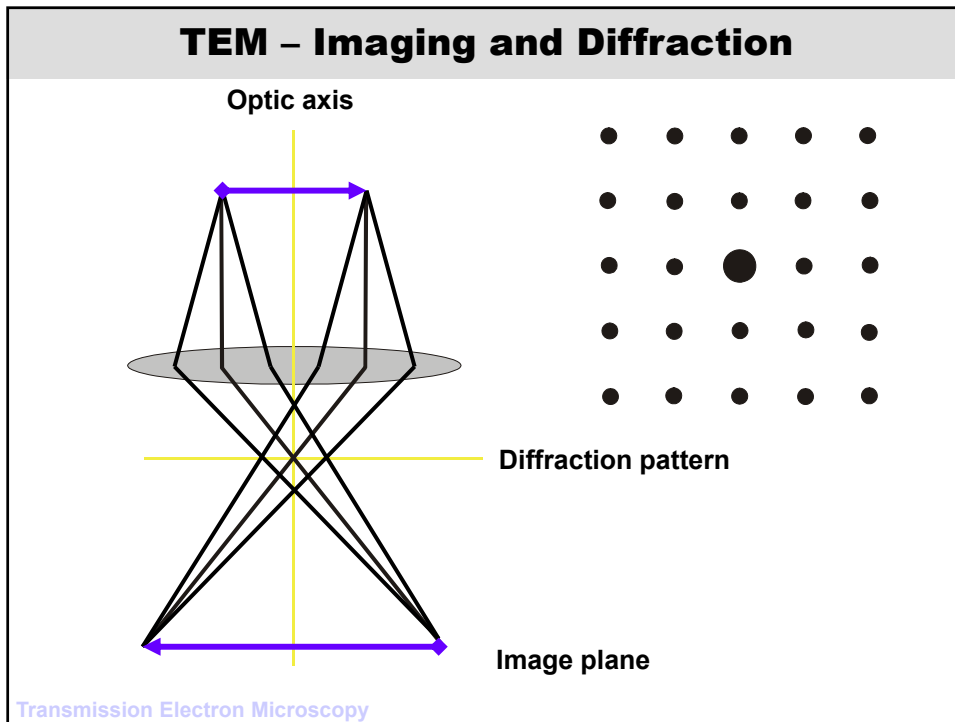


Transmission Electron Microscopy

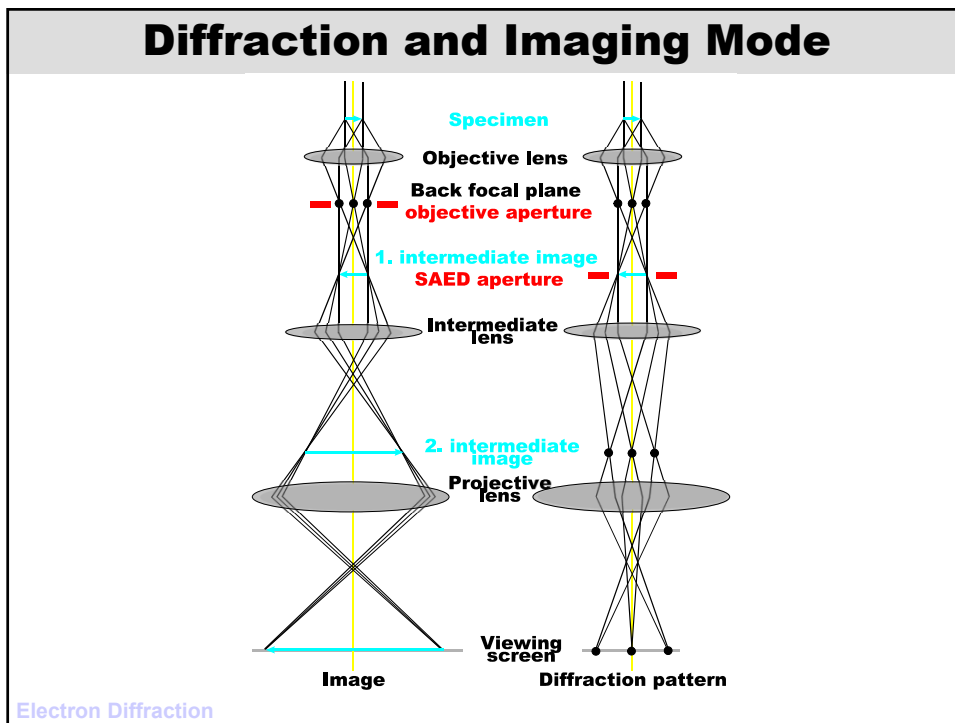
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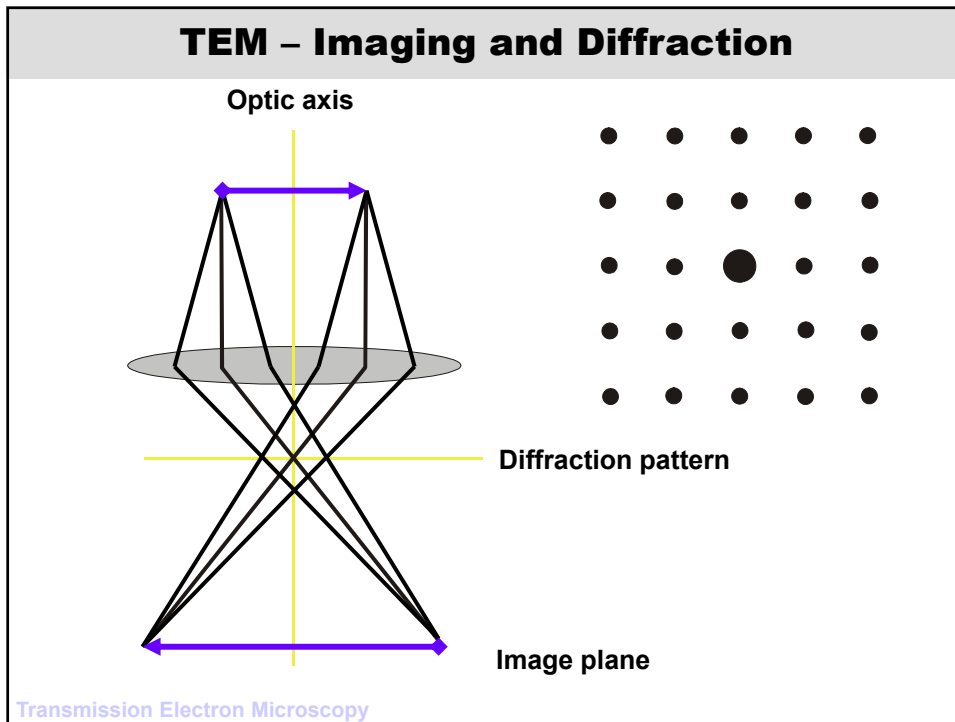
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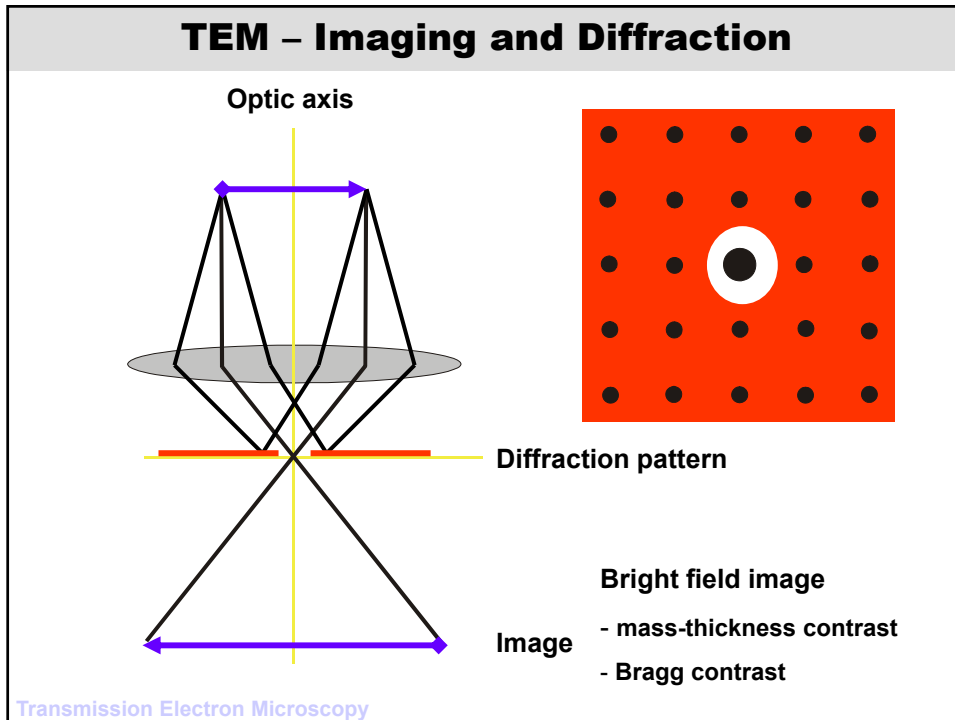
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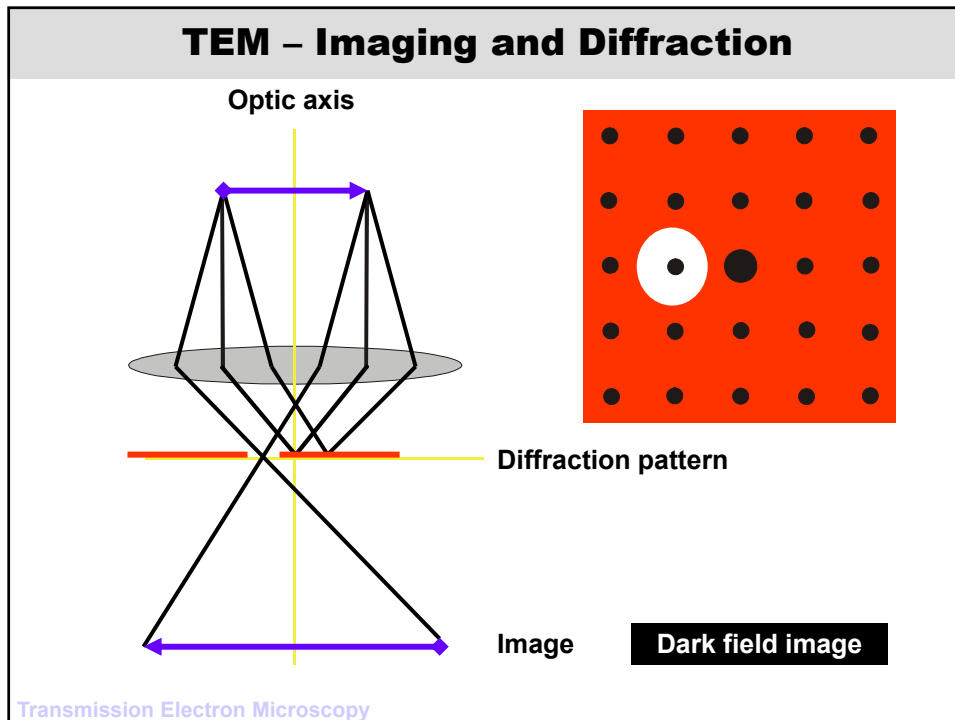
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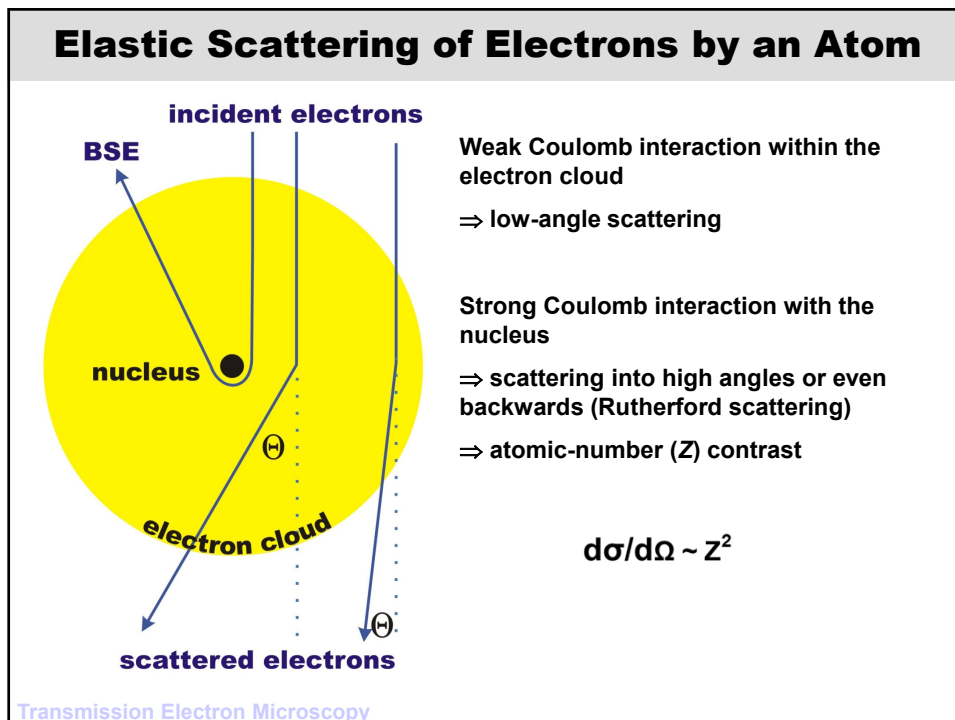
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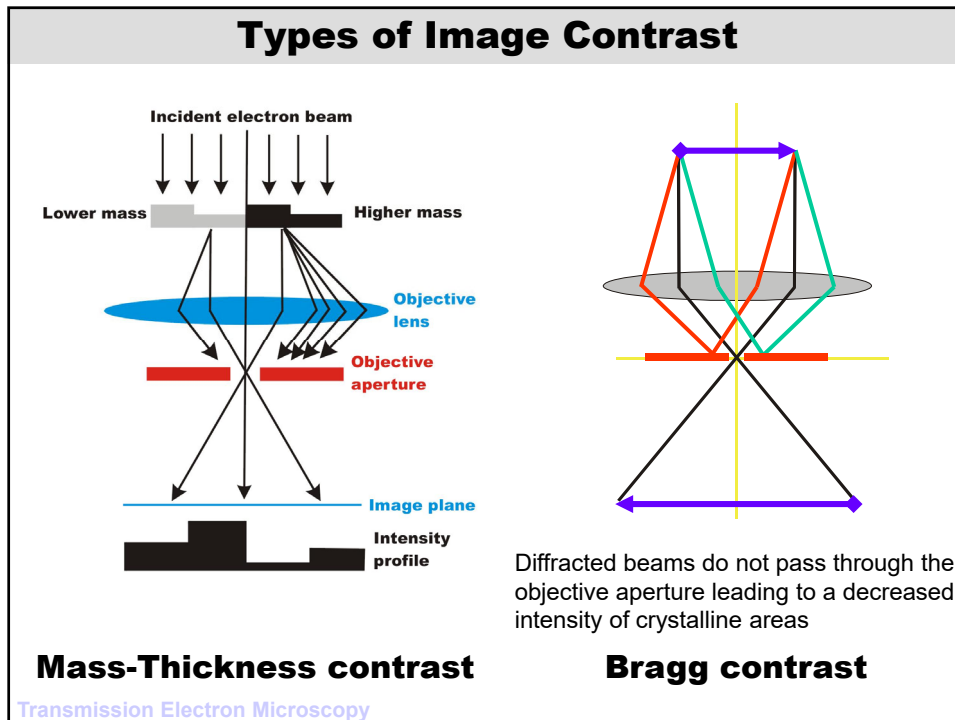
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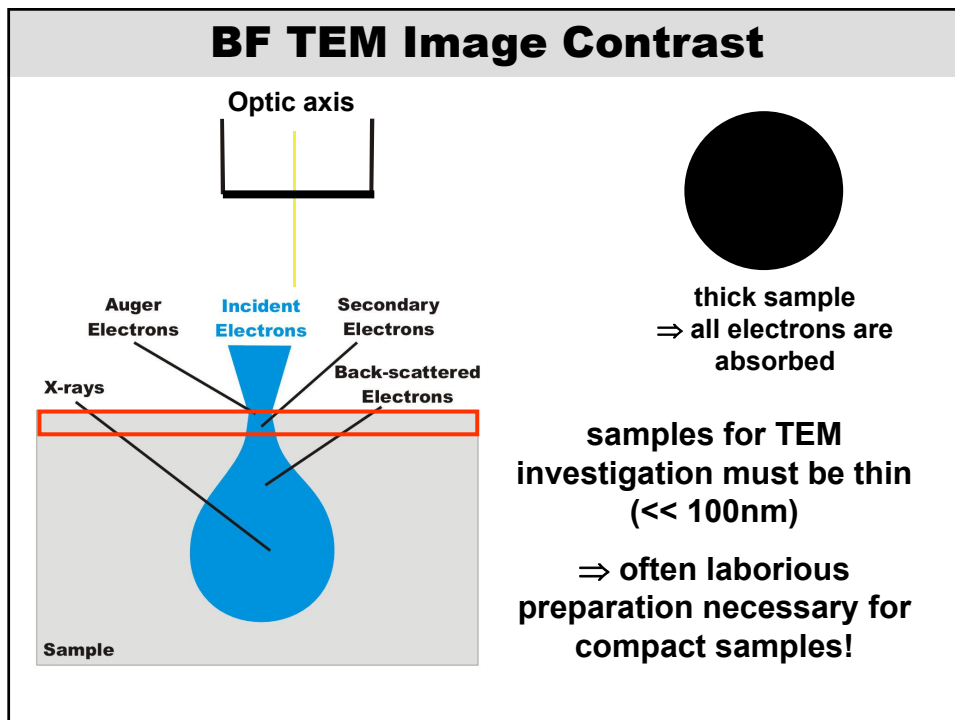
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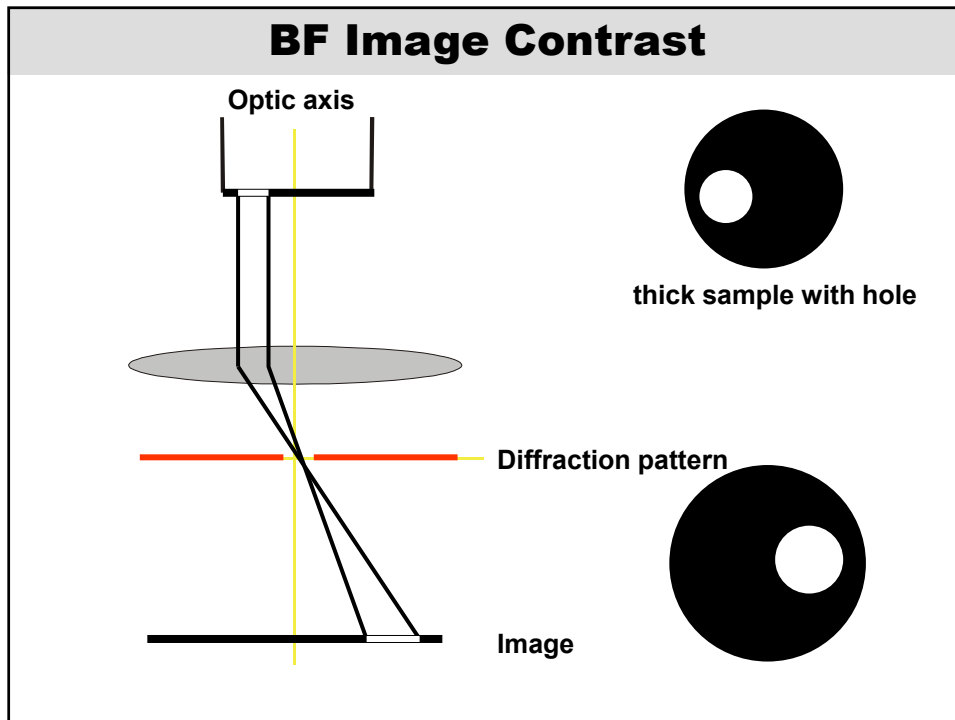
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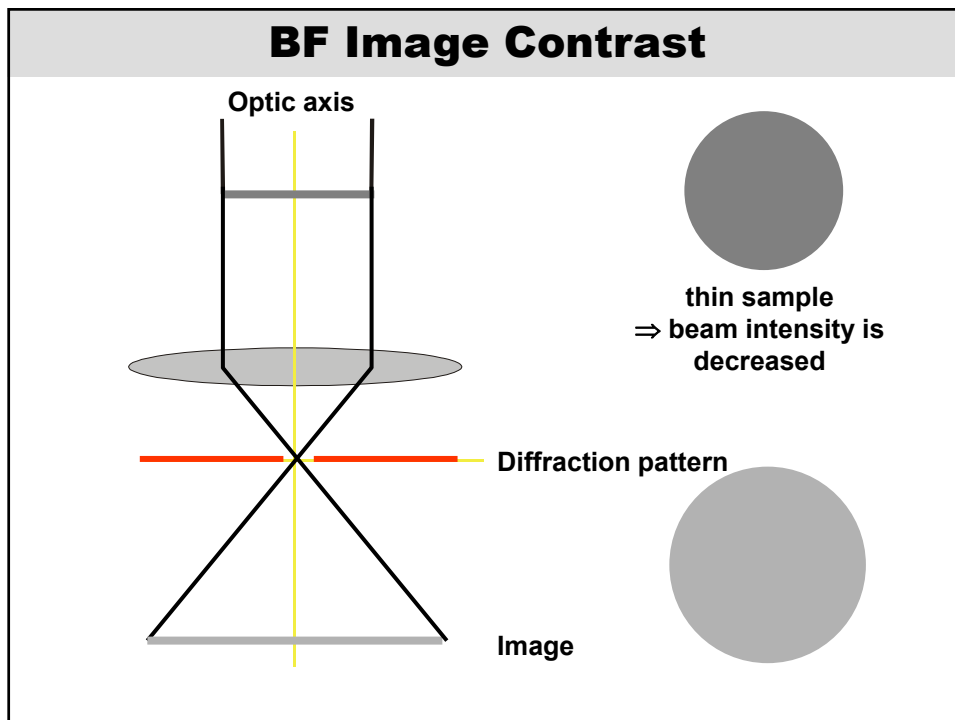
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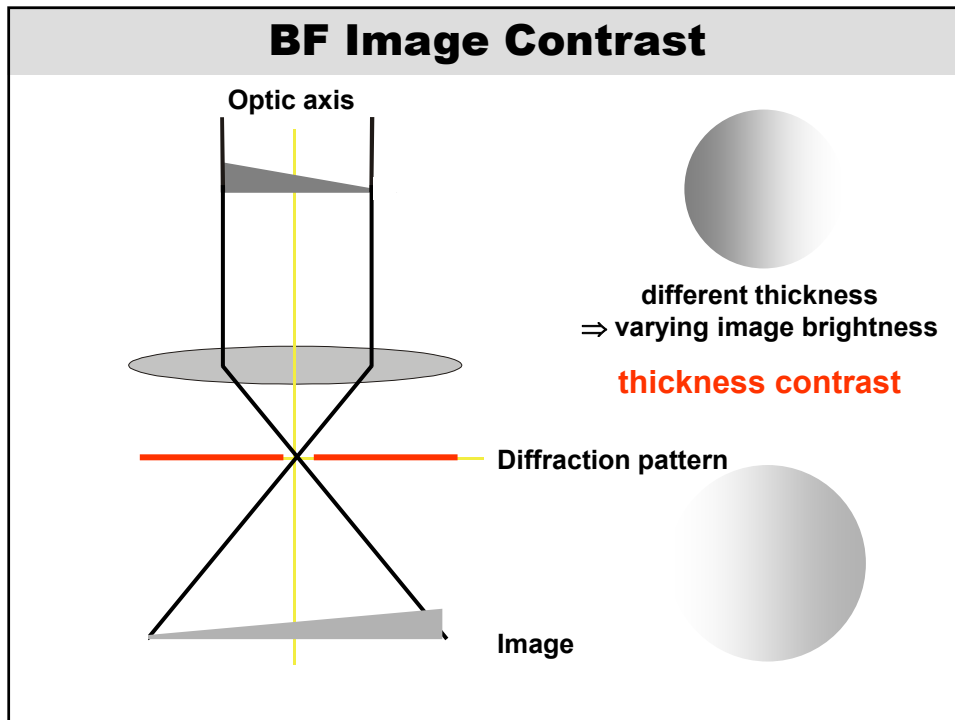
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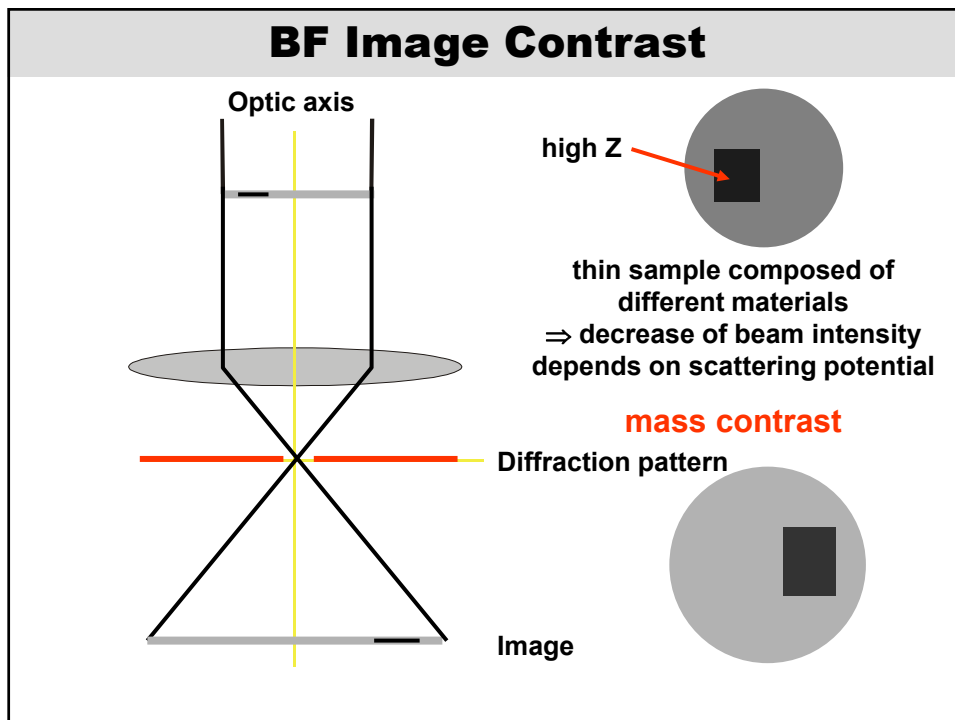
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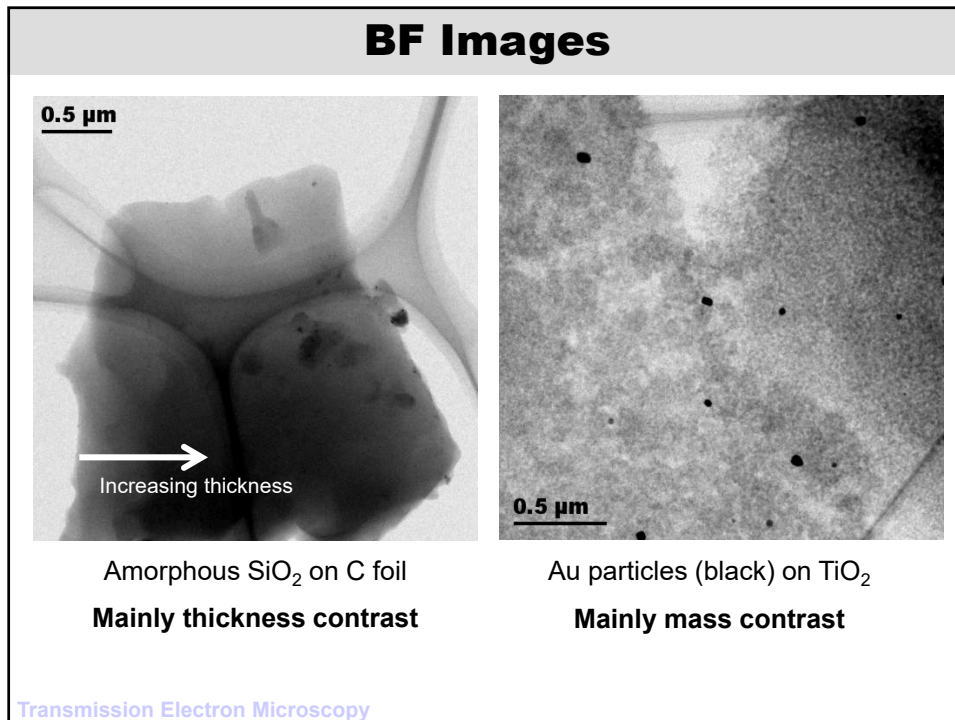
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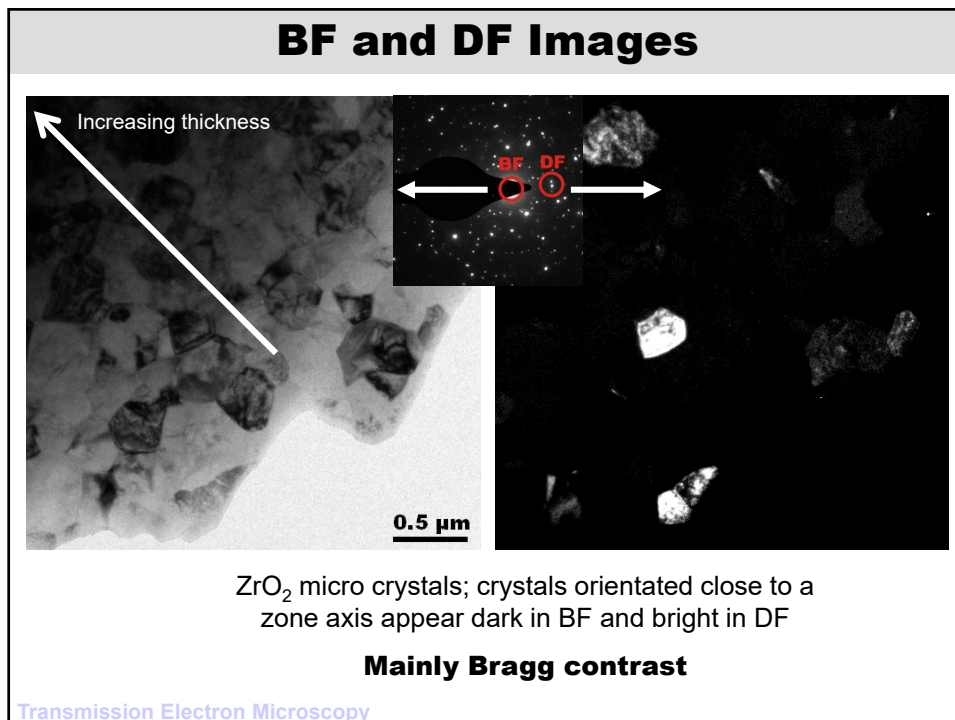
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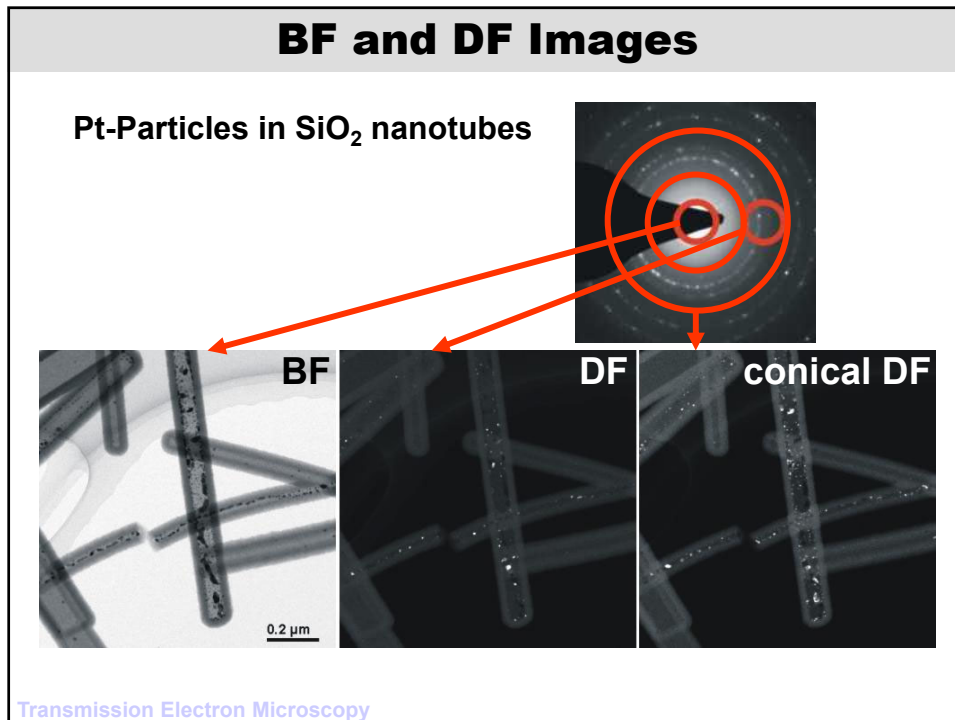
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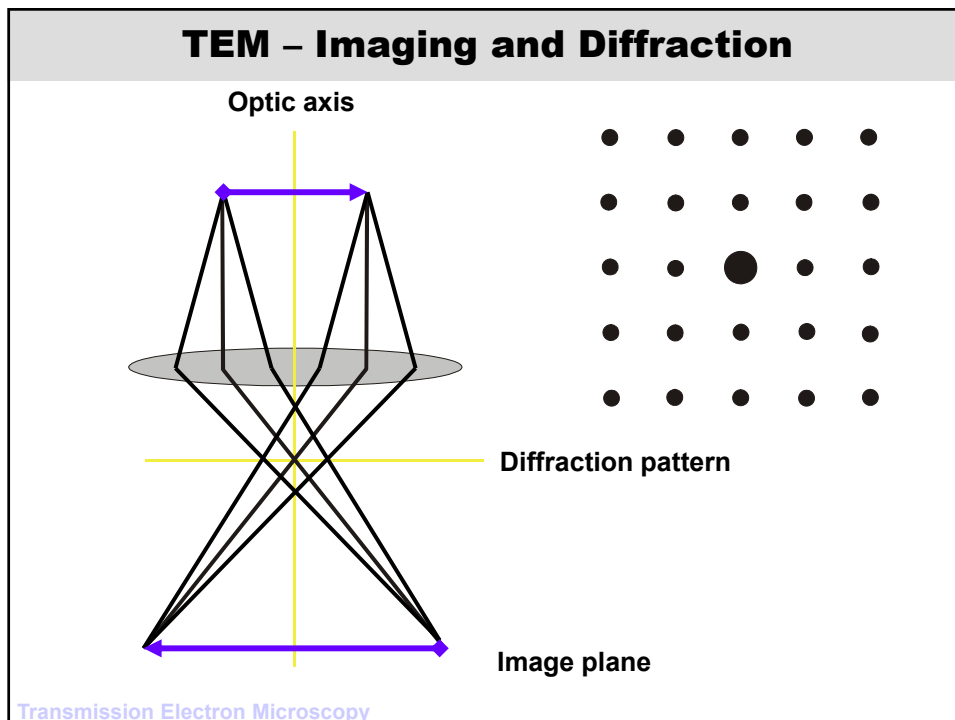
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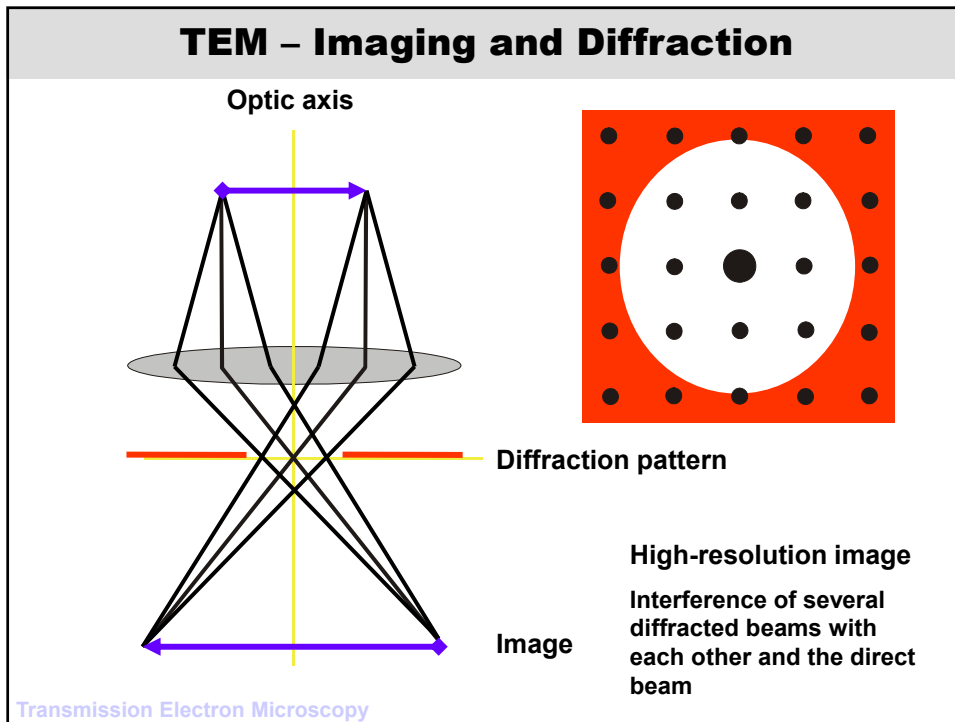
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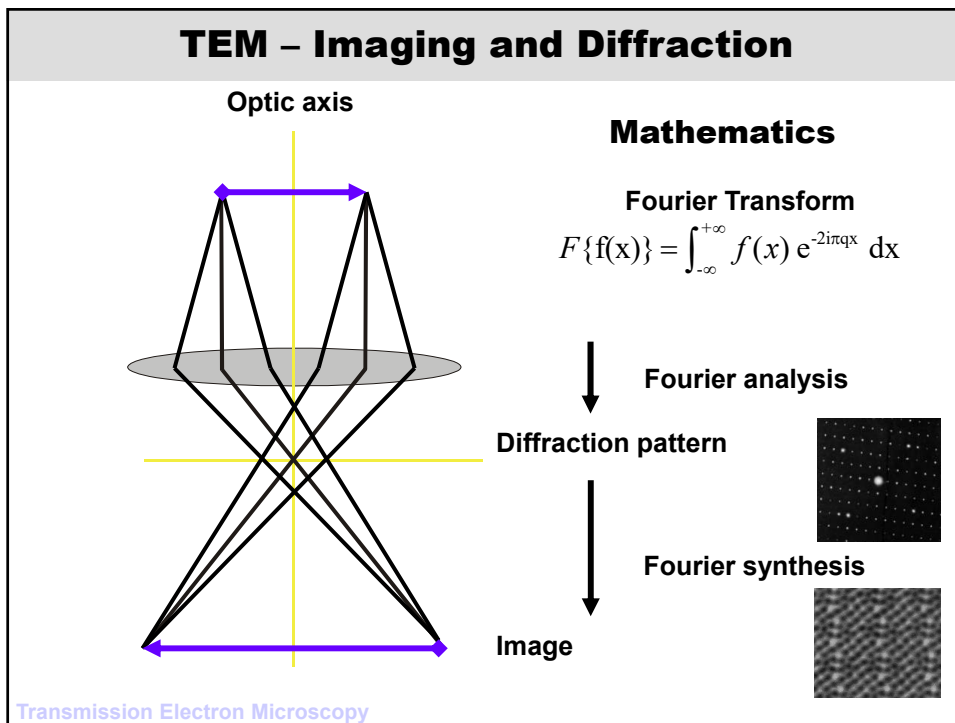
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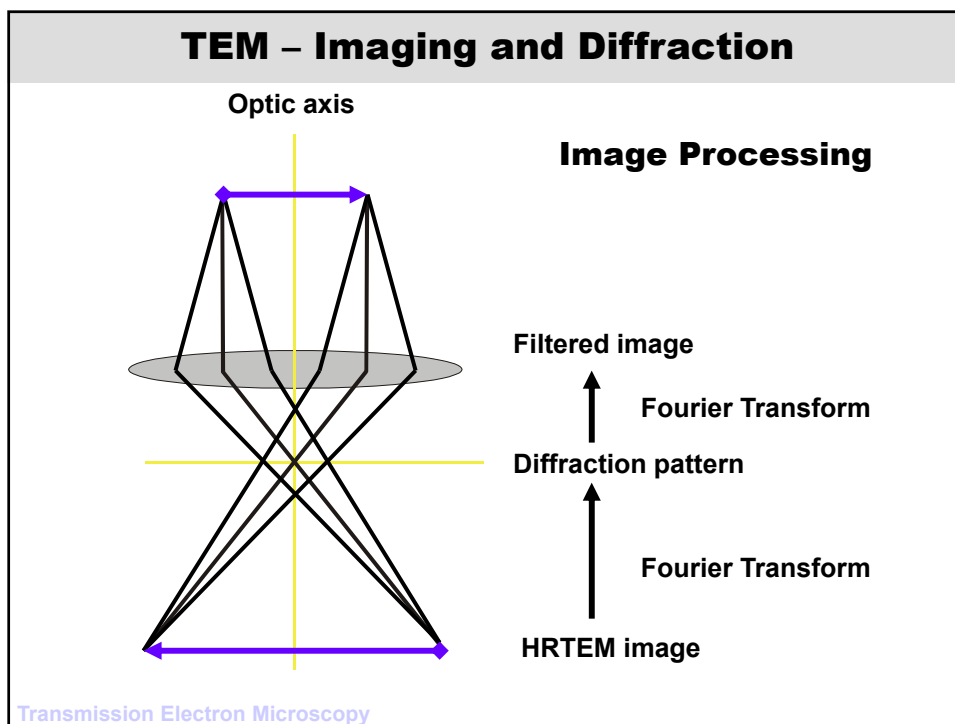
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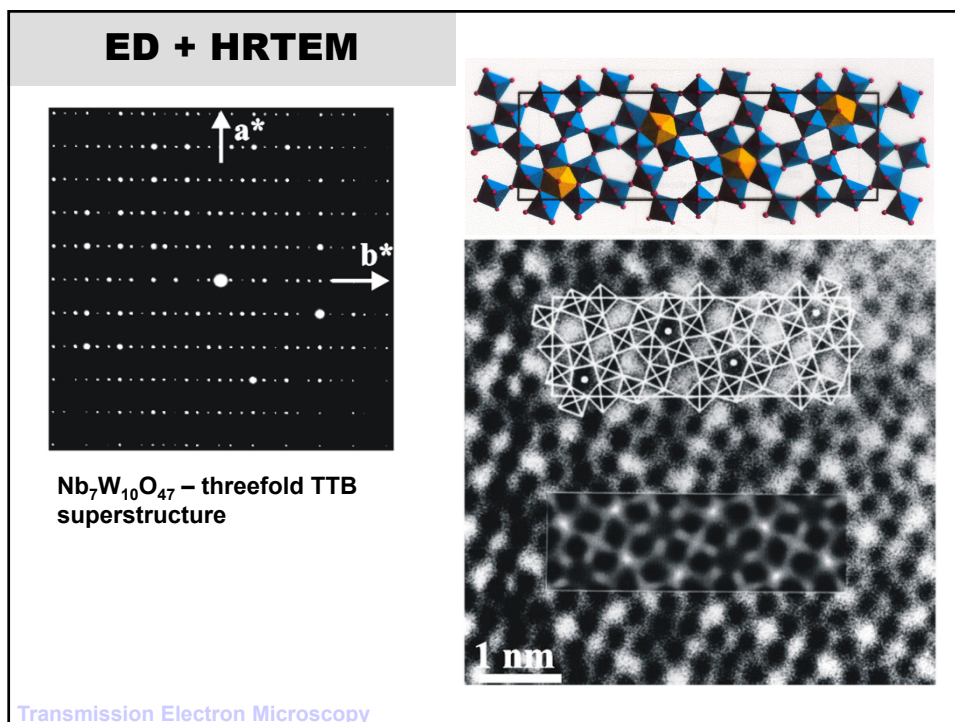
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28

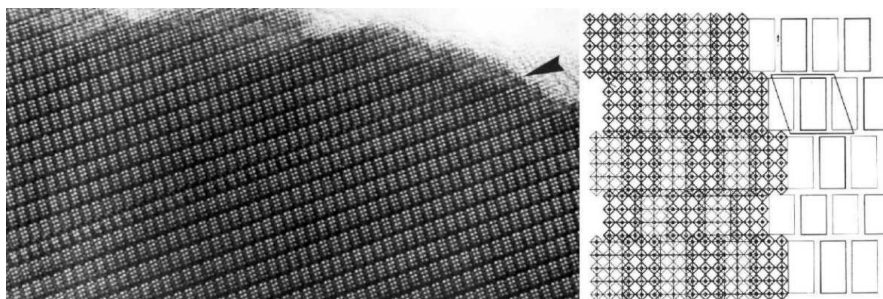


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HRTEM: Detection of Defects



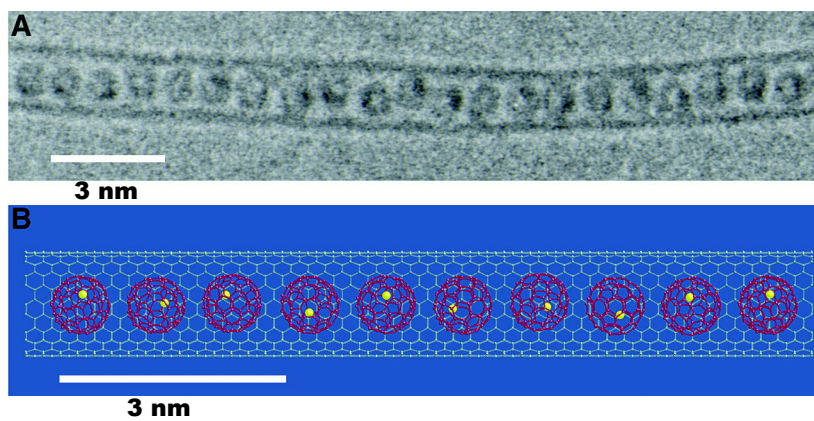
Planar defect in $\text{ZnNb}_{14}\text{O}_{35}\text{F}_2$

Transmission Electron Microscopy

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HRTEM: Imaging Single Atoms

Gd@C_{82} in SWCNT



Transmission Electron Microscopy

Suenaga et al, *Science* 290 (2000) 2280

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Projection Problem: 3D \Rightarrow 2D



Transmission Electron Microscopy

From: Williams, Carter: Transmission Electron Microscopy

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Transmission Electron Microscopy

Types of contrast:

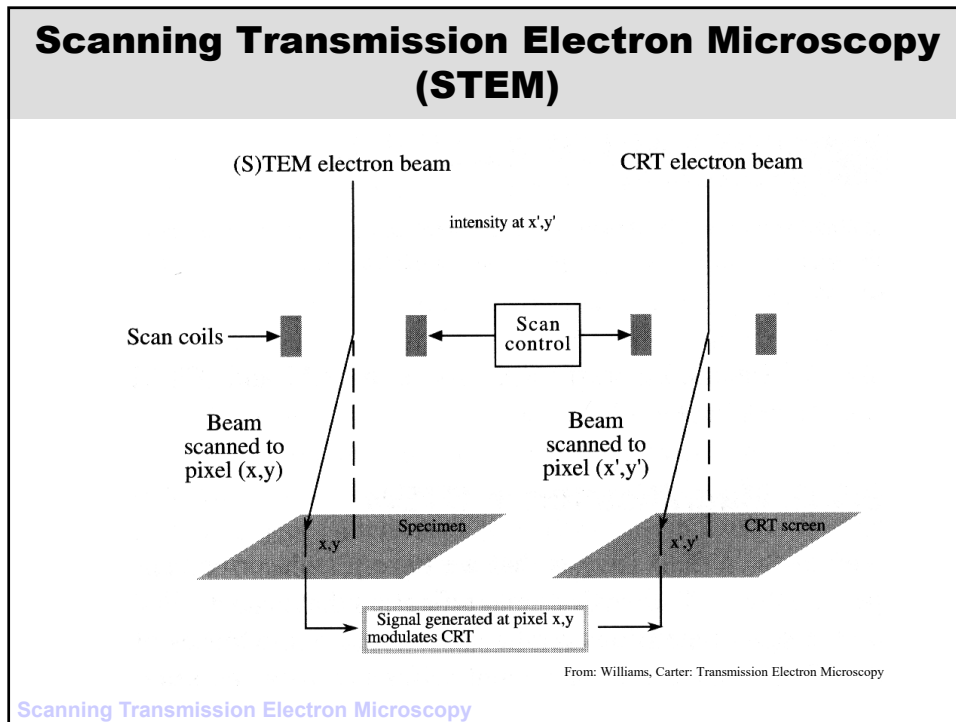
- Mass-thickness (BF/DF)
- Bragg (BF/DF)
- Phase (HRTEM; resolution limit $< 1\text{\AA}$)

Determination of

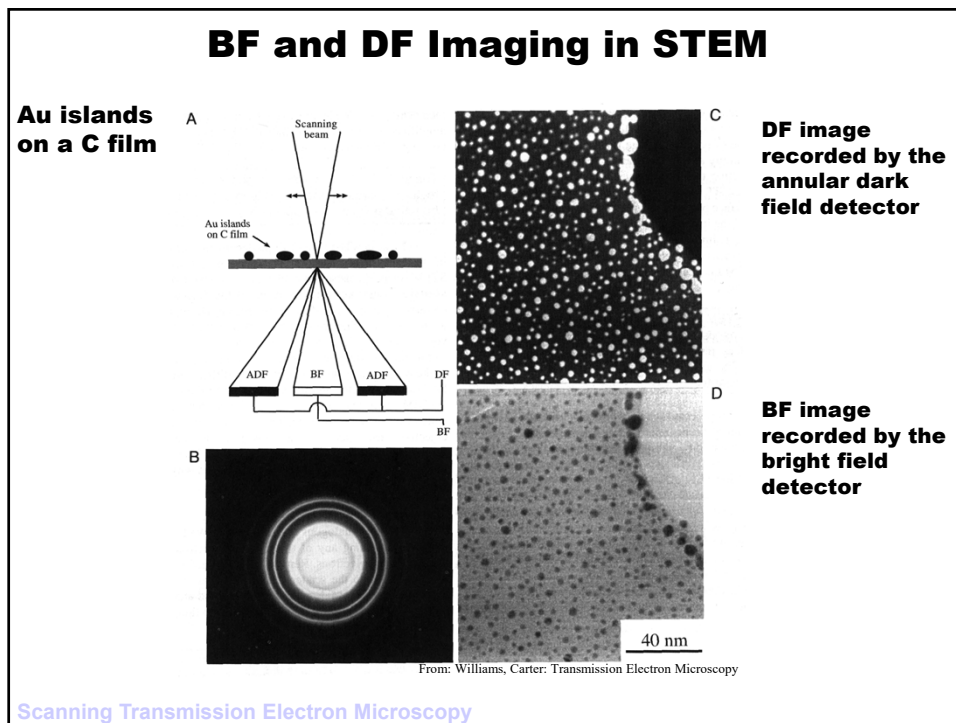
- Structure: HRTEM
- Defects: HRTEM, TEM
- Lattice constants and symmetry: ED
- Particle size: TEM, HRTEM

Transmission Electron Microscopy

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The diagram illustrates the geometry of STEM detectors. On the left, a 'Thin specimen' is shown with an 'Incident beam' passing through it. 'Scattered electrons' are shown at an angle θ with a differential angle $d\theta$, and 'Unscattered electrons' pass straight through. The solid angle is denoted as $d\Omega$. On the right, an 'Incident convergent beam' passes through a 'Specimen'. Three detector types are shown: 'HAADF detector' (High Angle Annular Dark Field), 'ADF detector' (Annular Dark Field), and 'BF detector' (Bright Field). The angular ranges for these detectors are defined as: $\theta_1 > 50$ mrad off axis, $\theta_2 > 10-50$ mrad, and $\theta_3 < 10$ mrad. A note states $10 \text{ mrad} \approx 0.57^\circ$. The source is cited as 'From: Williams, Carter: Transmission Electron Microscopy'.

STEM Detectors

BF: Bright Field detector
ADF: Annular Dark Field detector
HAADF: High Angle Annular Dark Field detector

Scanning Transmission Electron Microscopy

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Scattering of Electrons at an Atom

The diagram shows an atom with a central 'nucleus' and an outer 'electron cloud'. 'Incident electrons' approach from the top. Some interact with the 'electron cloud', resulting in 'Weak Coulomb interaction within the electron cloud' and 'low-angle scattering'. Others interact with the 'nucleus', resulting in 'Strong Coulomb interaction with the nucleus', which causes 'scattering into high angles or even backwards (Rutherford scattering)'. This leads to 'atomic-number (Z) contrast'. The differential cross-section is given by the equation $d\sigma/d\Omega \sim Z^2$. 'Backscattered electrons' (BSE) are shown as 'scattered electrons' moving away from the atom.

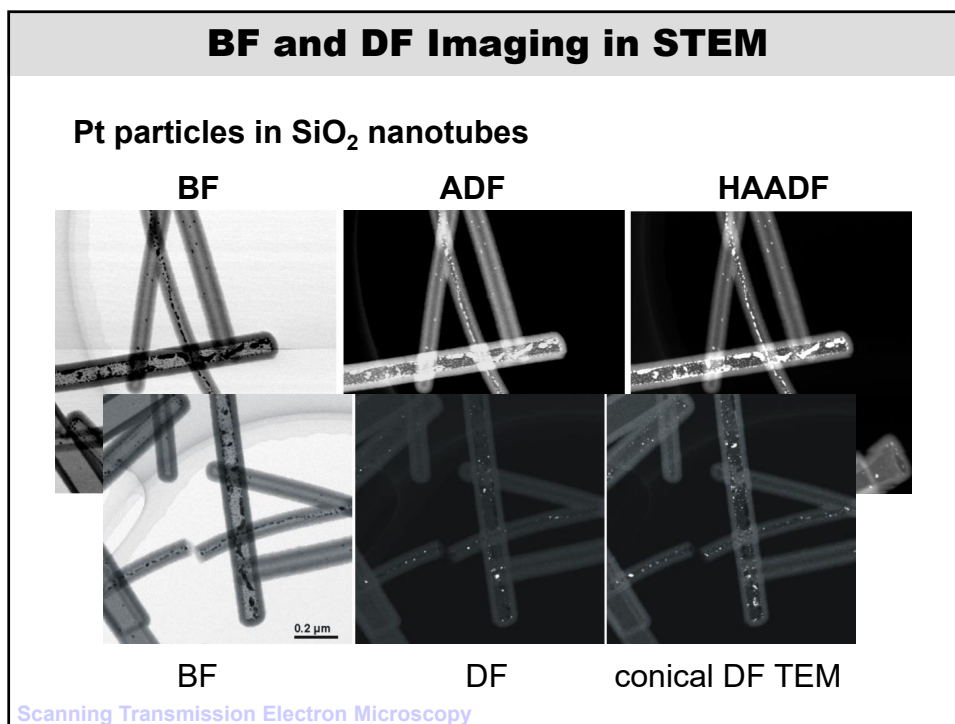
Weak Coulomb interaction within the electron cloud
 \Rightarrow low-angle scattering

Strong Coulomb interaction with the nucleus
 \Rightarrow scattering into high angles or even backwards (Rutherford scattering)
 \Rightarrow atomic-number (Z) contrast

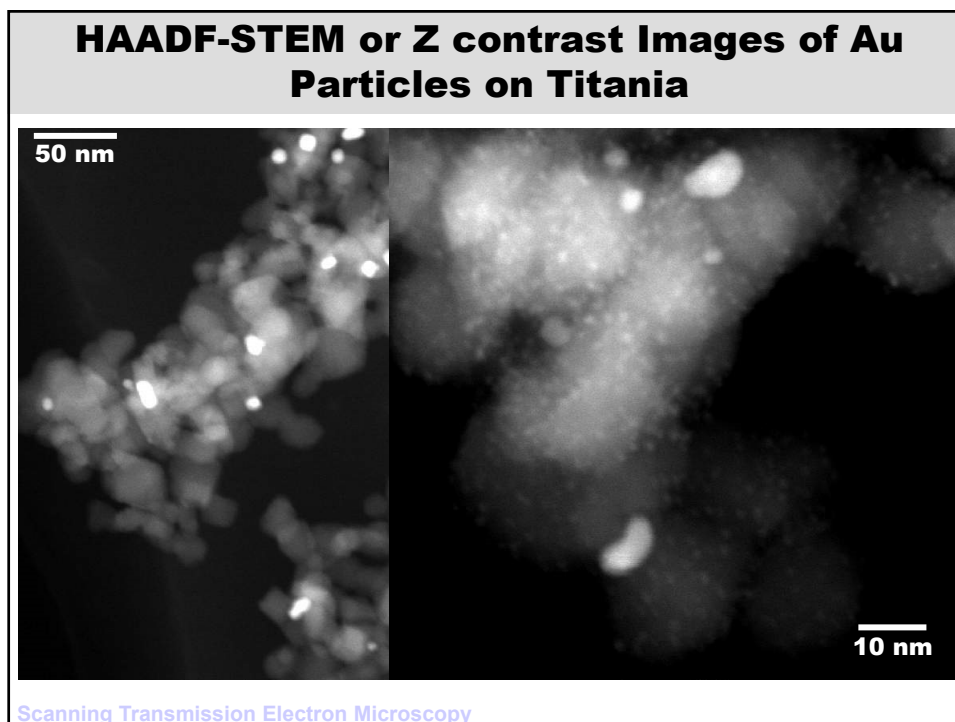
$d\sigma/d\Omega \sim Z^2$

Scanning Transmission Electron Microscopy

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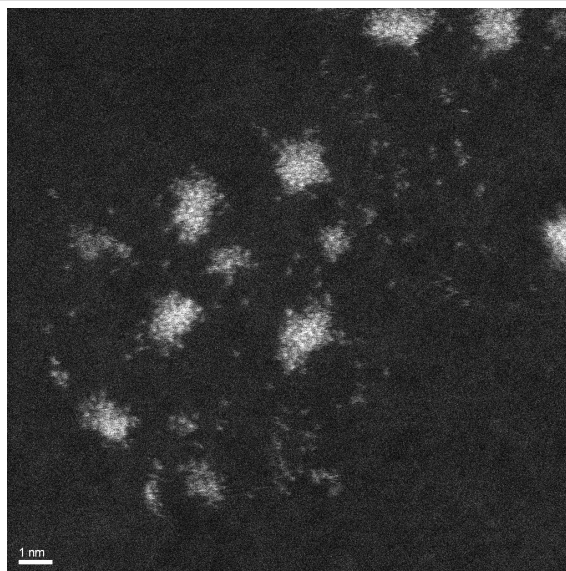


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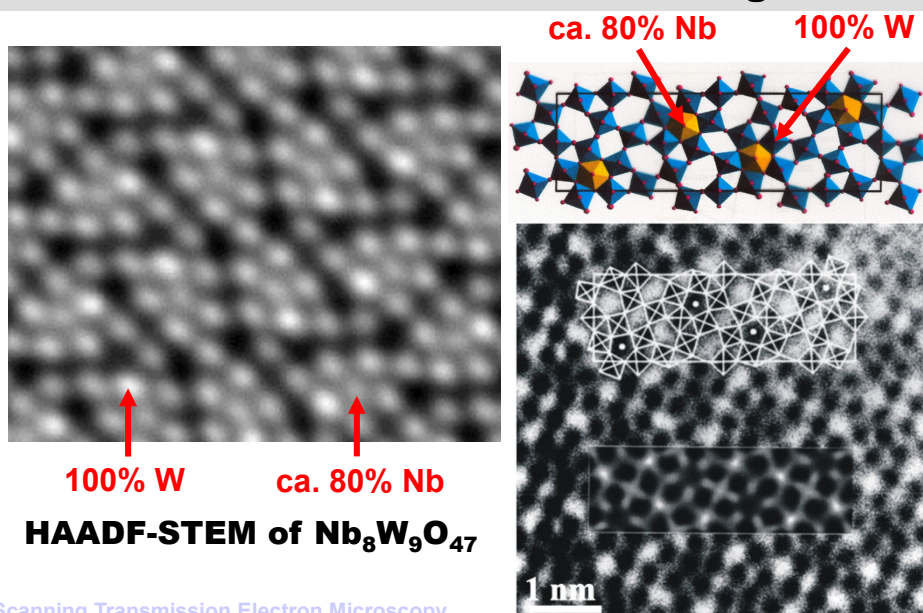
HAADF-STEM or Z contrast Images of Pt Clusters and Atoms on Carbon



Scanning Transmission Electron Microscopy

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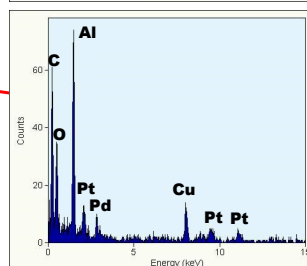
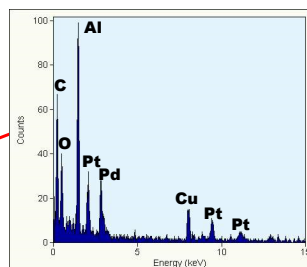
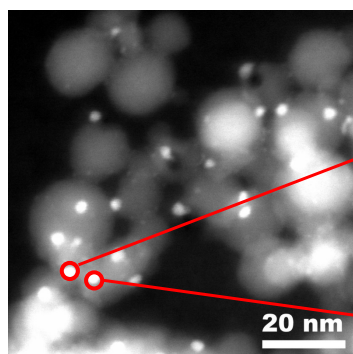
Information about Elemental Distribution in HAADF-STEM or Z contrast images



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Pd and Pt supported on alumina: Size of the particles? Alloy or separated?

STEM + EDXS: Point Analyses

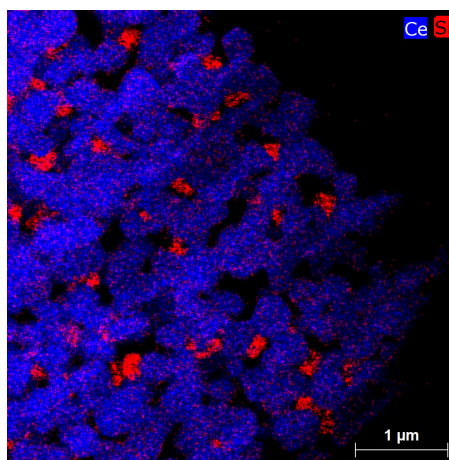
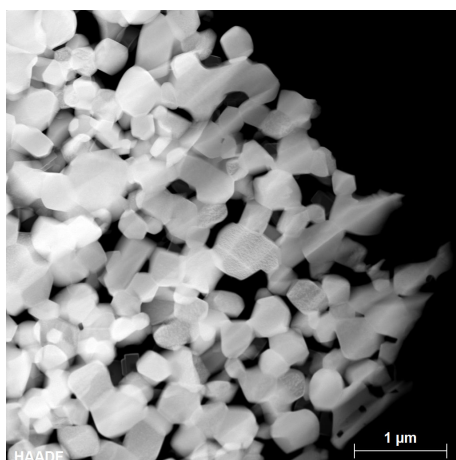


Scanning Transmission Electron Microscopy

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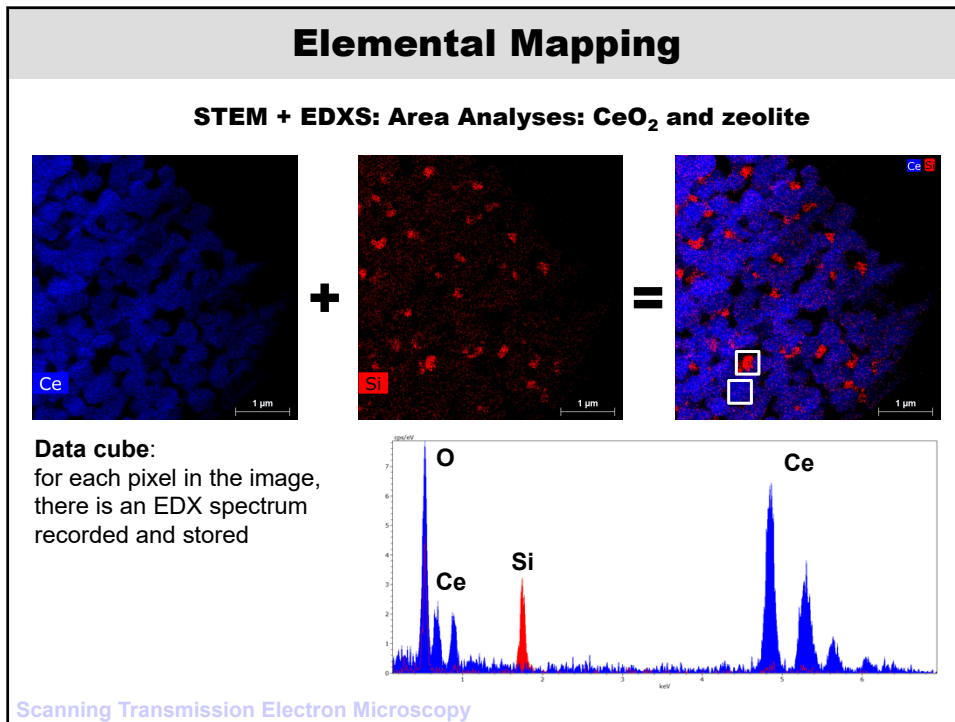
Elemental Mapping

STEM + EDXS: Area Analyses: CeO₂ and zeolite

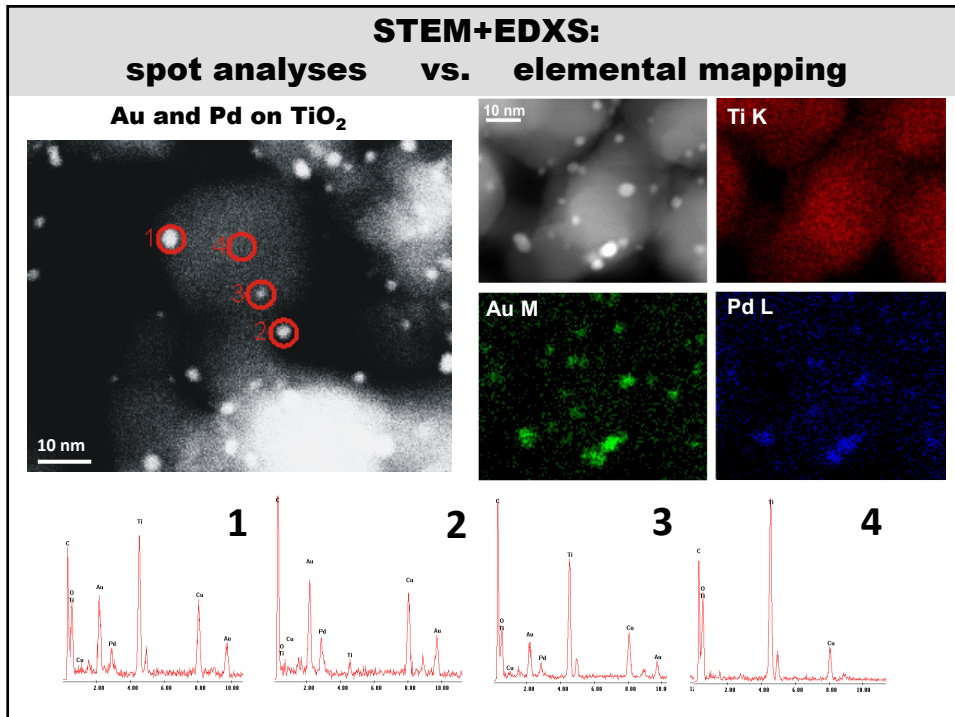


Scanning Transmission Electron Microscopy

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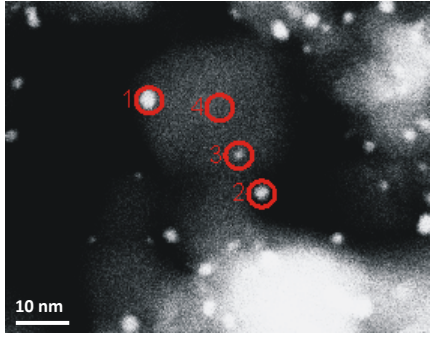


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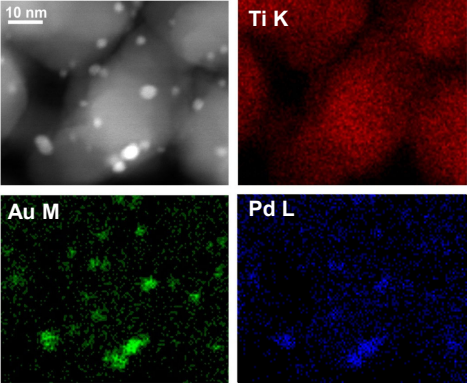
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**STEM+EDXS:
spot analyses vs. elemental mapping**



quick and efficient if a clear contrast between the different components appears in STEM

EDX spectra of selected spots with good signal:noise ratio measured in < 1 min



time-consuming but provides the full data cube (1EDXS/pixel)

EDX spectra extracted from selected spots with bad signal:noise ratio

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Scanning Transmission Electron Microscopy

Contrast:

- Mass-thickness (BF/DF)
- Bragg (BF/DF)
- Z^2 (HAADF)

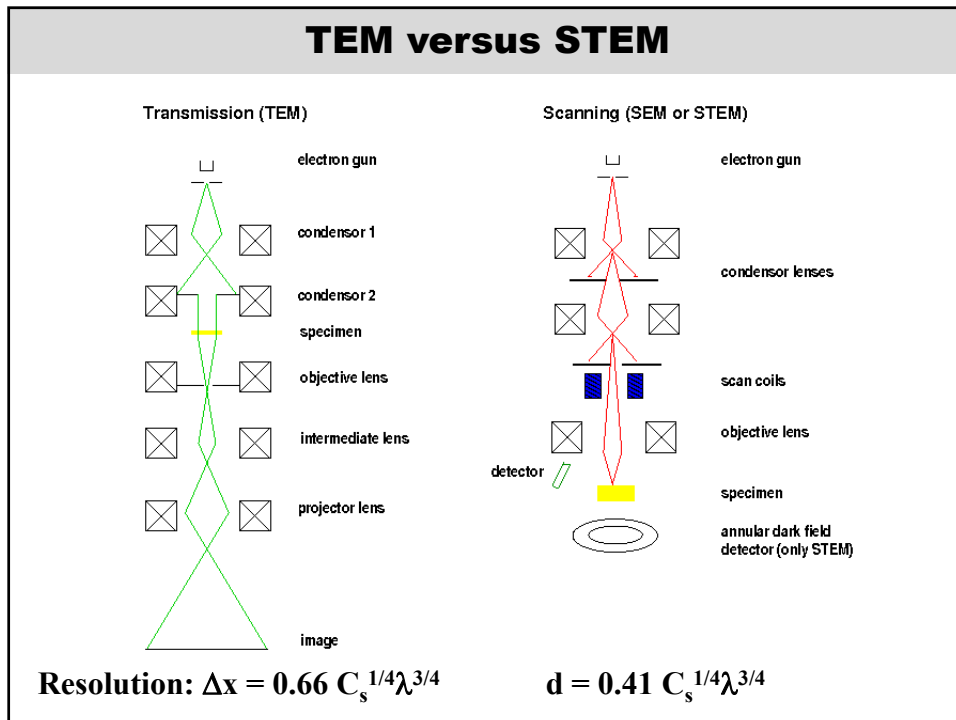
Determination of

- Particles on support : HAADF
- Structure and defects : HR
- Chemical information : HAADF

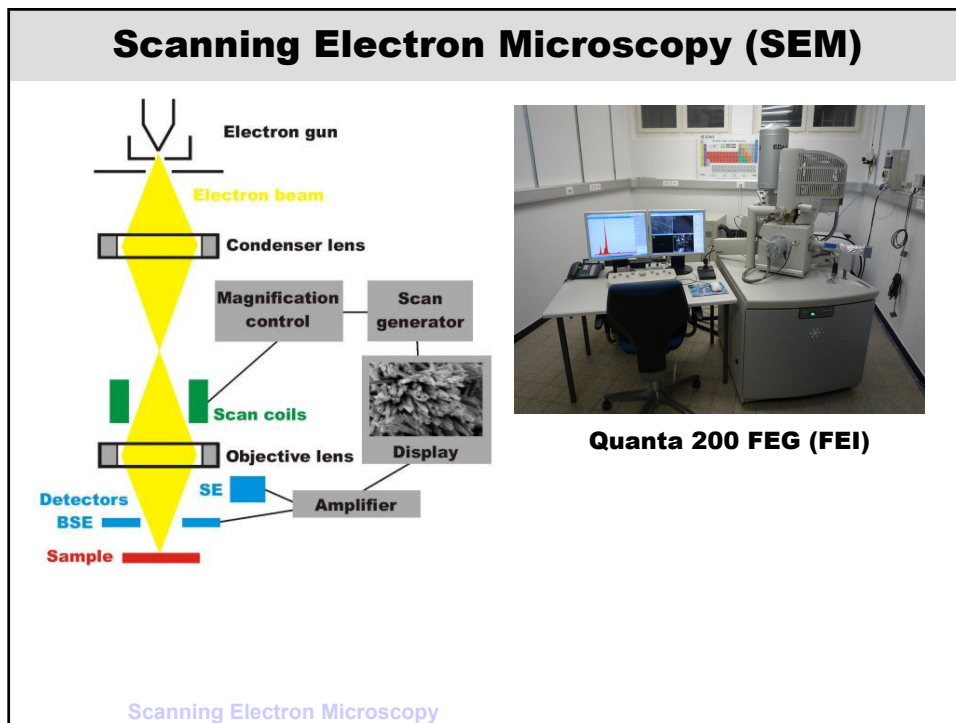
Important: Combination with EDXS or EELS

Scanning Transmission Electron Microscopy

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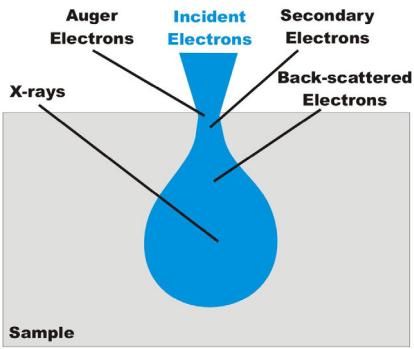


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Signals used in the SEM



The diagram illustrates the interaction of an incident electron beam with a sample. The incident electrons (blue) create a teardrop-shaped interaction volume. From this volume, several signals are generated: Auger electrons (small arrows pointing away from the surface), Secondary electrons (small arrows pointing away from the surface), Back-scattered electrons (larger arrows pointing away from the surface), and X-rays (small arrows pointing away from the surface).

Secondary Electrons (SE)

- low energy < 100 eV (result of inelastic interactions)
- information about topography and morphology
- escape only when generated close to the surface

Back-scattered Electrons (BSE)

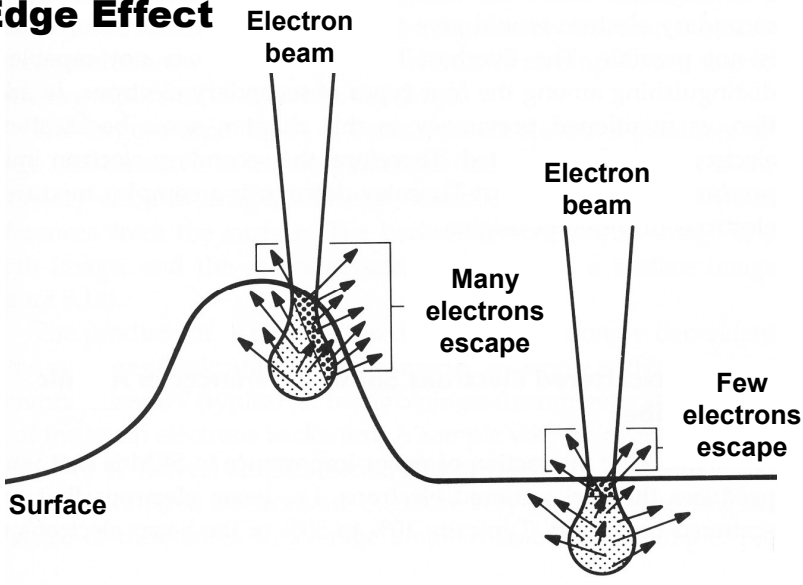
- high energy $\cong E_0$ (result of elastic interactions)
- morphology and chemical information

Scanning Electron Microscopy

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Topographic Contrast in the SEM

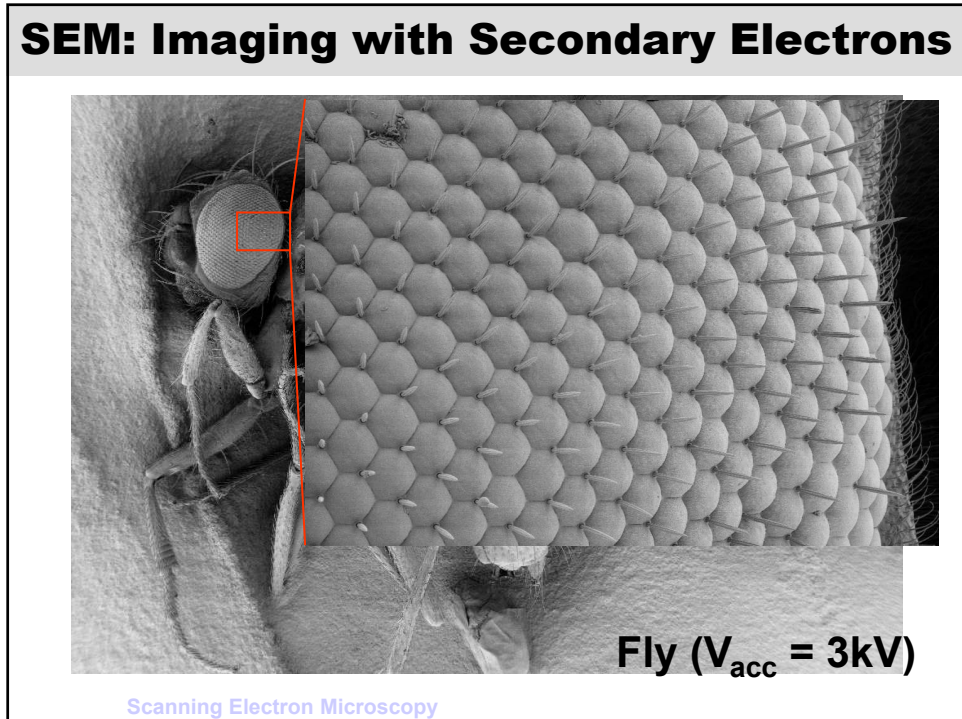
Edge Effect



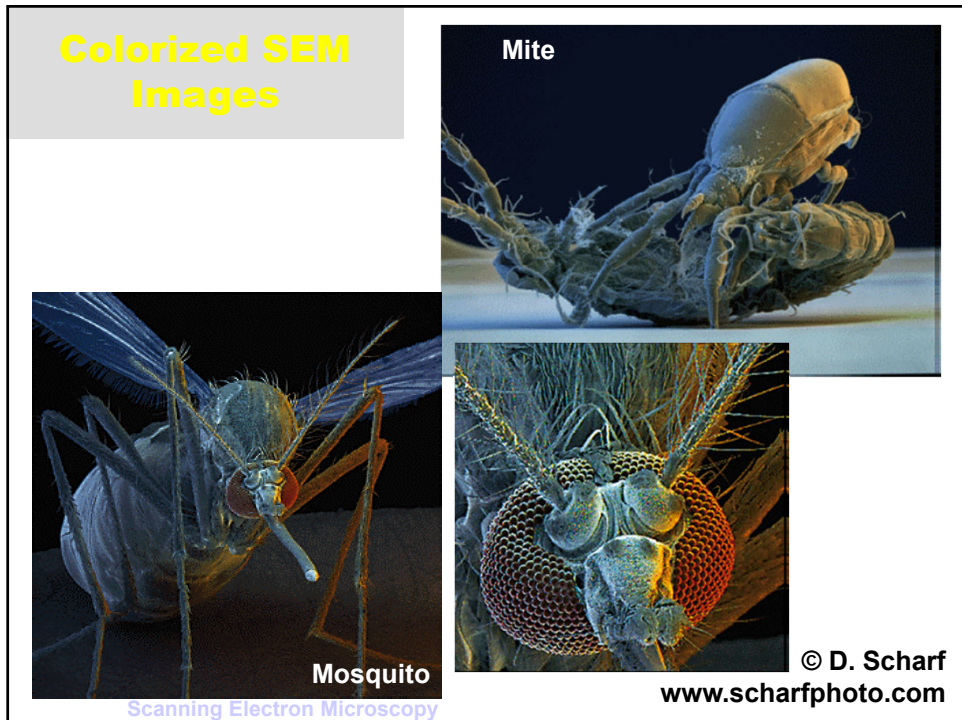
The diagram shows an electron beam hitting a surface at an edge. On the left, the beam hits the edge of a raised surface, and many electrons are shown escaping. On the right, the beam hits a flat surface, and few electrons are shown escaping. The surface is labeled 'Surface'.

Scanning Electron Microscopy

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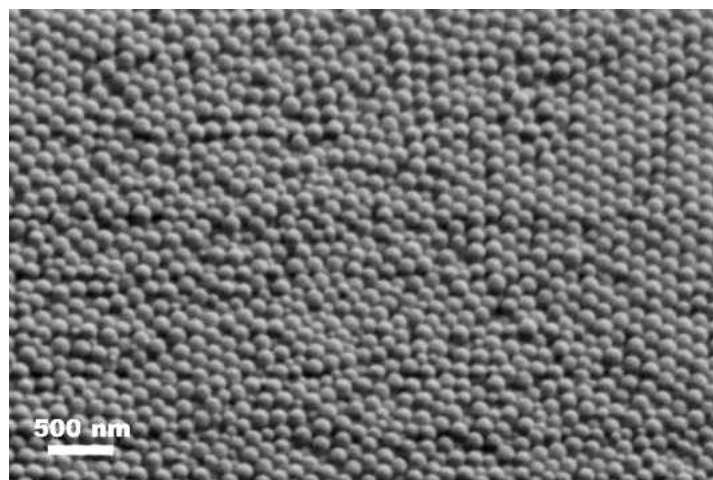


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SEM: Imaging with Secondary Electrons

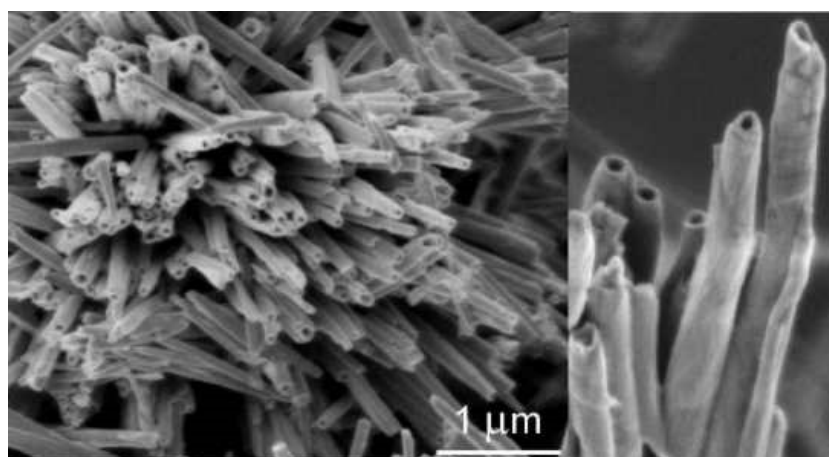


Latex balls ($V_{acc} = 1kV$)

Scanning Electron Microscopy

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SEM: Imaging with Secondary Electrons

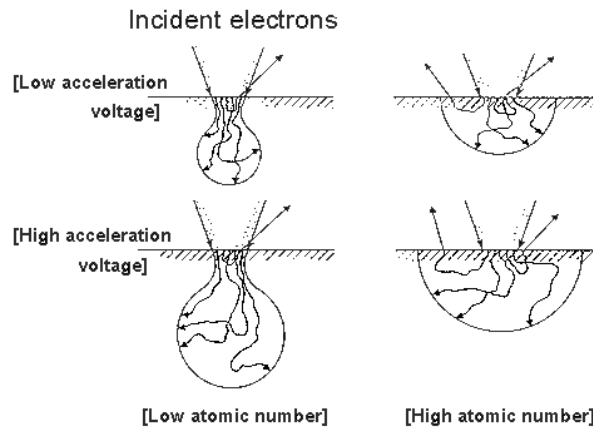


Vanadium oxide nanotubes ($V_{acc} = 1kV$)

Scanning Electron Microscopy

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SEM: Dependence on Electron Energy



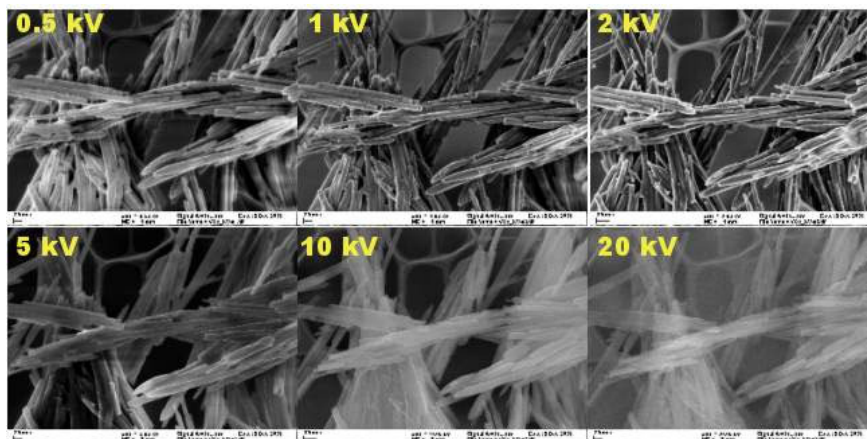
Penetration depth of electrons in matter

- increases with increasing V_{acc}
- decreases with increasing atomic number

Scanning Electron Microscopy

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SEM: Dependence on Electron Energy

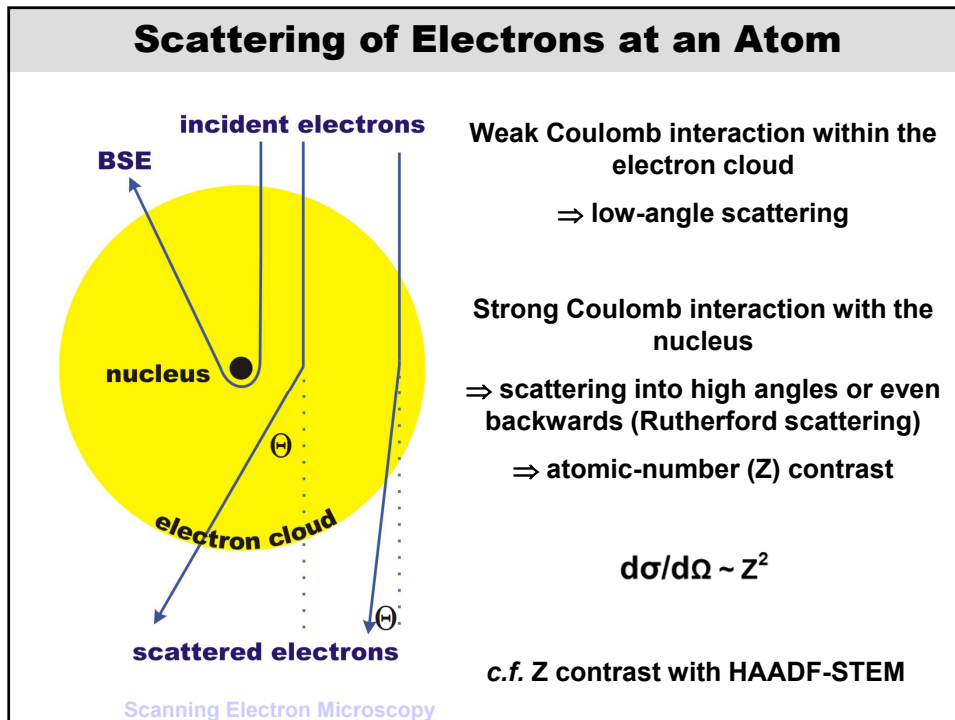


Resolution (Gemini 1530 FEG):

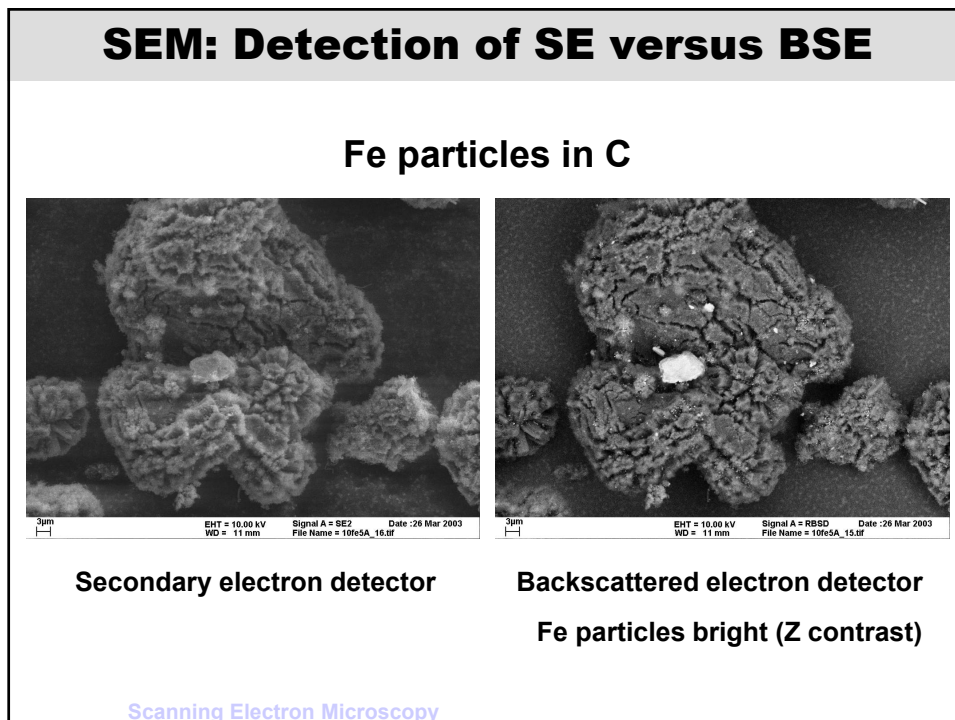
1 nm at 20 kV 1.5 nm at 10 kV
2.5 nm at 1 kV 5 nm at 0.2 kV

Scanning Electron Microscopy

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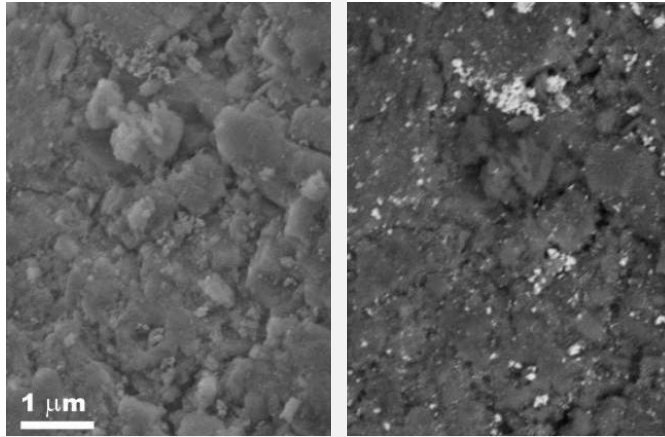
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SEM: Detection of SE versus BSE

Pt particles on alumina



Secondary electron detector

Backscattered electron detector

Pt particles bright (Z contrast)

Scanning Electron Microscopy

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Scanning Electron Microscopy (SEM)

Detection of:

- Secondary electrons
- Back-scattered electrons

Determination of

- Morphology
- Surface topology
- Particles of heavy elements

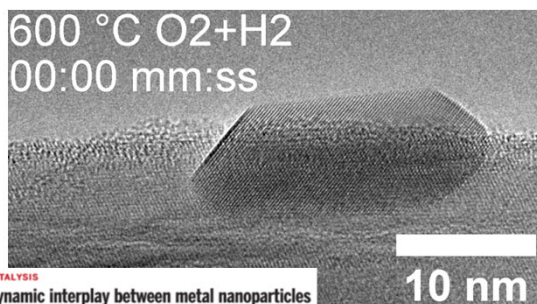
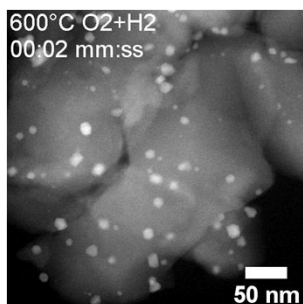
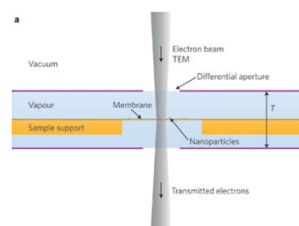
Combination with EDXS

Scanning Electron Microscopy

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In-situ investigations

- Heating
- Nano-indentation
- Electric conductivity
- Light
- Liquid and gas environment



CATALYSIS
Dynamic interplay between metal nanoparticles and oxide support under redox conditions

H. Frey^{1,2}; A. Beck^{2,3}; X. Huang^{1,4}; J. A. van Bokhoven^{2,3}; M. G. Willinger^{1,2}

Science 376, 982-987 (2022)

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**Scripts: *Interactions.pdf* and
Introduction into TEM and STEM on
www.microscopy.ethz.ch/downloads**

Textbooks:

Williams, Carter, Plenum Press, New York, 1996:
Transmission Electron Microscopy (available in chemistry library)

Thomas, Gemming, Springer, Berlin, 2014:
*Analytical Transmission Electron Microscopy – An Introduction
for Operators*
*Analytische Transmissionselektronenmikroskopie – eine
Einführung für den Praktiker*

Lecture: *Electron Microscopy* (each fall term)

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